



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Confirmation No. 5900**
Koki ICHIHASHI et al. : Docket No. 2003_0603A
Serial No. 10/606,805 : Group Art Unit 1725
Filed June 27, 2003 : Examiner Maria A. Elve

LASER IRRADIATION APPARATUS AND
METHOD

AMENDMENT

THE COMMISSIONER IS AUTHORIZED
TO CHARGE ANY DEFICIENCY IN THE
FEES FOR THIS PAPER TO DEPOSIT
ACCOUNT NO. 23-0975

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action of June 15, 2005, please amend the above-identified U.S. Patent application as follows: